REMARKS

Claims 22-32 were previously pending for examination in this application. Claims 1-21 and 33-41 were withdrawn. Claims 1-21 and 33-41 have now been canceled without prejudice or disclaimer. Claim 22-24, 27 and 29-32 have been amended. New method claims 42-60 have been added. As a result, claims 22-32 and 42-60 are pending for examination with claims 22 and 42 being independent claims. No new matter has been added.

Preliminary Matters

The Applicants note with appreciation that initialed copies of several Information Disclosure Statements (IDSs) submitted by the Applicants were attached to the Office Action mailed September 23, 2004. However, initialed copies of IDSs submitted on February 5, 2002 and July 26, 2002 were not provided to the Applicants. Copies of the IDSs submitted on February 5, 2002 and July 26, 2002 are provided herewith along with corresponding copies of postcards stamped by the USPTO. The Applicants respectfully request that initialed copies of the IDSs submitted on February 5, 2002 and July 26, 2002 be sent to the Applicants by the Examiner with the next correspondence.

Rejections Under 35 U.S.C. §102

Claims 22-32 were rejected under 35 U.S.C. §102(b) as allegedly being anticipated by U.S. Patent No. 5,867,302 to Fleming (hereinafter Fleming). The Applicants disagree with the Examiner's characterization of Fleming and respond as follows.

Claim 22 as amended recites "An electrostatically-actuated diffractive optical processor having ... an axis normal to at least a portion of a surface of [a] substrate ... comprising: a plurality of first mirror surfaces ...; [and] a plurality of second mirror surfaces, at least a portion of each of the plurality of second mirror surfaces ... optically adjacent to at least a corresponding one of the plurality of first mirror surfaces for light projected parallel to the axis." The term "optically adjacent surfaces" is defined on page 7, line 2 et. seq. as meaning surfaces that, for light of a specified angle of projection, are located such that when light is projected onto the surfaces at the specified angle, the light is projected onto one or the other surface, and substantially no light impinges on points between the surfaces.

An example of an optical processor having surfaces that are optically adjacent for light projected parallel to an axis is provided in FIG. 3 of the Applicants' specification, where surface 210b is optically adjacent to surface 215b for light 350 projected parallel to an axis Z which is normal to a surface of substrate 330.

By contrast, in FIG. 4b of Fleming (the figure to which the Office Action refers), Fleming discloses two mirror surfaces 38 and 38' that are not optically adjacent for light projected parallel to an axis perpendicular to a surface of a substrate. Rather, when light is projected parallel to an axis normal to a surface of substrate 12, the light is projected into a gap located between mirror surfaces 38 and 38'. In this regard, the device disclosed in Fleming is like the prior art optical processor discussed with reference to FIG. 1 of the Applicants' specification.

Accordingly, claim 22 is patentable over Fleming. Claims 23-32 depend from claim 22 and are patentable for at least the same reasons as claim 22. Withdrawal of these rejections is respectfully requested.

The Applicants note that other than the amendment to claim 22 regarding optical adjacency being specified for light projected parallel to the axis, as discussed above in the Remarks section, the remaining amendments to claim 22 and other claims are made to clarify the claimed subject matter and not for reasons of patentability.

New claims 42-51 depend from claim 22 and are patentable for at least the same reasons as claim 22.

New method claims 52-60 are patentable over Flemming at least because they recite a step of "providing ... an optical processor ... comprising ... second mirror surfaces optically adjacent to at least a corresponding one of [a] plurality of first mirror surfaces for light projected parallel to [an axis normal to at least a portion of a surface of a substrate of the optical processor]."

CONCLUSION

In view of the foregoing amendments and remarks, reconsideration is respectfully requested. This application should now be in condition for allowance; a notice to this effect is respectfully requested. If the Examiner believes, after this amendment, that the application is not

in condition for allowance, the Examiner is requested to call the Applicants' attorney at the telephone number listed below.

If this response is not considered timely filed and if a request for an extension of time is otherwise absent, the Applicants hereby request any necessary extension of time. If there is a fee occasioned by this response, including an extension fee, that is not covered by an enclosed check, please charge any deficiency to Deposit Account No. 50/2762.

Respectfully submitted, Erik R. Deutsch, et al., Applicants

By:

Geffrey B. Powers, Reg. No. 45,021 LOWRIE, LANDO & ANASTASI, LLP

One Main Street

Cambridge, Massachusetts 02142

United States of America Telephone: 617-395-7000 Facsimile: 617-395-7070

Docket No.: P0743/7001 (SJH)
Date: December 22, 2004



Serial No. 69/975, 169 File No. Po743 Title: Actiatable D. ffractive Optical Application of Exik R. Deutsch efal	
The U.S. PTO Mail Room acknowledges receipt of the following	on the date stamped hereon:
[] Mailing by Express Mail (37 CFR 1.10) Express Mail Label No	Provisional Application Cover Sheet Multiple Dependent Claim Fee Sheet Inf. Discl. Statement, PTO Form 1449 [
[] Other	,
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ATTORNEY'S DOCKET NO: P0743/7001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Erik R. Deutsch et al.

Serial No:

09/975,169

Filed:

October 11, 2001

For:

Actuatable Diffractive Optical Processor

Examiner:

Not Yet Assigned

Art Unit:

2872

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, Washington, D.C. 20231, on the day of February, 2002.

Steven J. Henry Reg. No. 27,900

Commissioner For Patents Washington, D.C. 20231

Sir:

Transmitted herewith are the following documents:

[X] Information Disclosure Statement, PTO Form 1449 and references

[X] Return Receipt Postcard

If the enclosed papers are considered incomplete, the Mail Room and/or the Application Branch is respectfully requested to contact the undersigned at (617) 720-3500, Boston, Massachusetts.

No check is enclosed to cover the filing fee. If the fee is insufficient, the balance may be charged to the account of the undersigned, Deposit Account No. 23/2825. A duplicate of this sheet is enclosed.

Respectfully Submitted,

Steven J. Henry

Reg. No. 27,900

Wolf, Greenfield & Sacks, P.C.

600 Atlantic Avenue

Boston, MA 02210-2211

(617) 720-3500

Docket No:

P0743/7001

Date:

February 5, 20

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DEC 2 7 2004 ATTORNEY'S DOCKET NO: P0743/7001 (SJH)

ED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Erik Deutsch, et al.

Serial No:

09/975,169

Filed:

October 11, 2001

For:

ACTUATABLE DIFFRACTIVE OPTICAL PROCESSOR

Examiner:

Not Yet Assigned

Art Unit:

2872

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, Washington, D.C. 20231, on the day of February, 2002.

Steven J. Henry, Reg. No. 27,900

Commissioner for Patents Washington, D.C. 20231

STATEMENT FILED PURSUANT TO THE DUTY OF DISCLOSURE UNDER 37 CFR §§1.56, 1.97 AND 1.98

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. §§1.56, 1.97 and 1.98, the Applicant requests consideration of this Information Disclosure Statement.

PART I: Compliance with 37 C.F.R. §1.97

This Information Disclosure Statement has been filed before the mailing date of a first Office Action on the merits in the above-identified case. No fee or certification is required.

PART II: Information Cited

The Applicant hereby makes of record in the above-identified application the information listed on the attached form PTO-1449 (modified). The order of presentation of the references should not be construed as an indication of the importance of the references.

Art Unit: 2872

<u>PART III: Explanation of Non-English Language References and Remarks Concerning Other Information Cited</u>

The following is a concise explanation of the relevance of each non-English language reference listed on the attached form PTO-1449 (modified):

The following are remarks concerning the other information cited:

PART IV: Remarks

Documents cited on the attached form PTO-1449 (modified) are enclosed unless otherwise indicated on the attached form PTO-1449 (modified). It is respectfully requested that:

- 1. The Examiner consider completely the cited information, along with any other information, in reaching a determination concerning the patentability of the present claims;
- 2. The enclosed form PTO-1449 be signed by the Examiner to evidence that the cited information has been fully considered by the Patent and Trademark Office during the examination of this application;
- 3. The citations for the information be printed on any patent which issues from this application.

By submitting this Information Disclosure Statement, the Applicant makes no representation that a search has been performed, of the extent of any search performed, or that more relevant information does not exist.

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, material to patentability as defined in 37 C.F.R. §1.56(b).

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, in fact, prior art as defined by 35 U.S.C. §102.

Notwithstanding any statements by the Applicant, the Examiner is urged to form his own conclusion regarding the relevance of the cited information.

Art Unit: 2872

An early and favorable action is hereby requested.

Respectfully submitted, Erik Deutsch et al., Applicant(s)

Steven J. Henry, Reg. No. 27,9000 Wolf, Greenfield & Sacks, P.C. 600 Atlantic Avenue Boston, MA 02210 Telephone (617) 720-3500

Docket No. P0743/7001 Dated: February 5, 2002

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FORM PTO-1449/A and B (Modified)

Sheet

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

of

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APPLICATION NO.:

09/975,169

ATTY. DOCKET NO.: P0743/7001

FILING DATE:

October 11, 2001

APPLICANT:

Erik Deutsch et al.

GROUP ART UNIT:

2872

EXAMINER: Not Yet Assigned

U.S. PATENT DOCUMENTS

Examiner's	Cite	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication or of issue	
Initials# No.		Number	Kind Code	Document	of Cited Document MM-DD-YYY	
		4,731,670		Allen et al.	03-15-1988	
		4,805,038		Seligson	02-14-1989	
		5,115,344		Jaskie	05-19-1992	
		5,212,582		Nelson	05-18-1993	
		5,781,670		Deacon et al.	07-14-1998	
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		5,847,859		Murata	12-08-1998	
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		5,905,589		Tanaka et al.	05-18-1999	
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		6,072,620		Shiono et al.	06-06-2000	
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		6,130,770		Bloom	10-10-2000	
		6,144,481		Kowarz et al.	11-07-2000	
		6,175,443	B1	Aksyuk et al.	01-16-2001	
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		6,233,087	B1	Hawkins et al.	05-15-2001	
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Examiner's	Cite	Cite Foreign Patent Document	Cite Foreign Patent Document Name of Patentee or Applicant of Cited	Foreign Patent Document		Name of Patentee or Applicant of Cited	Date of Publication of	Translation
Initials#			Document (not necessary)	Cited Document MM-DD-YYYY	(Y/N)			
		WO	91/02991	A·1		03-07-1991		
		WO	98/41893	Al		09-24-1998		
<u></u>		wo	01/11394	Al		02-15-2001		

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APPLICATION NO.:	09/975,169	ATTY. DOCKET NO.: P0743/7001
FILING DATE:	October 11, 2001	
APPLICANT:	Erik Deutsch et al	
GROUP ART UNIT:	2872	EXAMINER: Not Yet Assigned
	FILING DATE: APPLICANT:	FILING DATE: October 11, 2001 APPLICANT: Erik Deutsch et al.

FOREIGN PATENT DOCUMENTS

Examiner's Initials#	Cite No.	Fo	oreign Patent Docui	ment	Name of Patentee or Applicant of Cited Document (not necessary)	Date of Publication of Cited Document MM-DD-YYYY	Translation (Y/N)
		wo	01/11396	Aī		02-15-2001	
·		EP	1 122 577 A2			08-08-2001	
·		EP	1 143 287 A2			10-10-2001	

OTHER ART -- NON PATENT LITERATURE DOCUMENTS

Examiner's Initials#	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.			
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EXAMINER	DATE CONSIDERED

#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Serial No. 09/975/69 File No. P07/3 Title: Actuable Diffractive Option Application of Folia R. Devices on the control of the	AL PROCESSON
Application of FRIK R. DEUTSCH FTBL	WGS Date:
The U.S. PTO Mail Room acknowledges receipt of the following [] Mailing by Express Mail (37 CFR 1.10)	Provisional Application Cover Sheet Multiple Dependent Claim Fee Sheet Inf. Discl. Statement, PTO Form 1449 References Cited Proprity Document(s) #
[] Other	AUG 0 1 2002
DATE MAILED 7-36-03	TRADENDER ST



Attorney's Docket No. P0743/7001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Erik R. DEUTSCH, Malcolm C. SMITH, Michael A. BUTLER and Stephen D. SENTURIA

Serial No.:

09/975,169

Filing Date:

October 11, 2001

For:

ACTUABLE DIFFRACTIVE OPTICAL PROCESSOR

Examiner:

Unassigned

Art Unit:

2872

Confirmation No. 9099

Commissioner for Patents Washington, D.C. 20231

Sir/Madam:

Transmitted herewith for filing is/are the following document(s):

[X] Supplemental Information Disclosure Statement

[X] PTO Form 1449 With Cited References

[X] Return Post Card

If the enclosed papers are considered incomplete, the Mail Room and/or the Application Branch is respectfully requested to contact the undersigned collect at (617)720-3500, Boston, Massachusetts.

No check is enclosed. If it is determined that a fee is necessary, the fee may be charged to the account of the undersigned, Deposit Account No. 23/2825. A duplicate of this sheet is enclosed.

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

I hereby certify that this document is being placed in the United States mail with first-class postage attached, addressed to the Commissioner for Patents, Washington, D.C. 20231 on July 26, 2002.

Respectfully submitted,

ERIK R. DEUTSCH et al.

Jeffrey B. Powers

Registration No. 45,021

WOLF, GREENFIELD & SACKS, P.C.

600 Atlantic Avenue

Boston, MA 02210

Tel. (617)720-3500

Attorneys for the Applicant(s)

Attorney's Docket No. P0743/7001



Attorney's Docket No. P0743/7001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Erik R. DEUTSCH, Malcolm C. SMITH, Michael A. BUTLER and Stephen D. SENTURIA

Serial No.:

09/975,169

Filing Date:

October 11, 2001

For:

ACTUABLE DIFFRACTIVE OPTICAL PROCESSOR

Examiner:

Unassigned

Art Unit:

2872

Confirmation No. 9099

Commissioner for Patents Washington, D.C. 20231

SUPPLEMENTAL STATEMENT FILED PURSUANT TO THE DUTY OF DISCLOSURE UNDER 37 CFR §1.56, 1.97 AND 1.98

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. §§1.56, 1.97 and 1.98, the Applicant requests consideration of this Information Disclosure Statement.

Compliance with 37 C.F.R. §1.97

This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits in the above-identified case. No fee or certification is required.

Information Cited

The Applicant hereby makes of record in the above-identified application the information listed on the attached form PTO-1449 (modified). The order of presentation of the references should not be construed as an indication of the importance of the references.

REMARKS

Documents cited on the attached form PTO-1449 (modified) are enclosed unless otherwise indicated on the attached form PTO-1449 (modified). It is respectfully requested that:

1. The Examiner consider completely the cited information, along with any other information, in reaching a determination concerning the patentability of the present claims;

Serial No. 09/795,169

- 2 -

Art Unit: 2872

2. The enclosed form PTO-1449 be signed by the Examiner to evidence that the cited information has been fully considered by the Patent and Trademark Office during the examination of this application;

3. The citations for the information be printed on any patent which issues from this application.

By submitting this Information Disclosure Statement, the Applicant makes no representation that a search has been performed, of the extent of any search performed, or that more relevant information does not exist.

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, material to patentability as defined in 37 C.F.R. §1.56(b).

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, in fact, prior art as defined by 35 U.S.C. §102.

Notwithstanding any statements by the Applicant, the Examiner is urged to form his own conclusion regarding the relevance of the cited information.

An early and favorable action is hereby requested.

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

I hereby certify that this document is being placed in the United States mail with first-class postage attached, addressed to the Commissioner for Patents, Washington, D.C. 20231 on July 26, 2002.

Attorney's Docket No. P0743/7001

Respectfully submitted,

ERIK R. DEUTSCH et al.

Jeffrey B. Powers

Registration No. 45,021

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600 Atlantic Avenue

Boston, MA 02210

Tel. (617)720-3500

Attorneys for the Applicant(s)

FORM PTO-1449/A and B (Modified)

INFORMATION DISCEOSURE

STATEMENT BY APPLICANT

APPLICANT:

BY APPLICANT:

APPLICANT:

APPLICANT:

Erik R. Deutsch et al.

2872

EXAMINER:

U.S. PATENT DOCUMENTS

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of

Sheet

GROUP ART UNIT:

Examiner's	Cite	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication or of issue of Cited Document
Initials # No.	Number	Kind Code	Document	MM-DD-YY	
·····		3,553,364		Lee	01/05/71
	 	4,234,788		Palmer et al.	11/18/80
	 -	5,022,745		Zayhowski et al.	06/11/91
	 	5,164,688		Larson	11/17/92
	 	5,168,249		Larson	12/01/92
		5,175,521		Larson	12/29/92
	+	5,206,557		Bobbio	04/27/93
	 -	5,212,582		Nelson	05/18/93
		5,291,502		Pezeshki et al.	03/01/94
	+	5,353,641		Tang	10/11/94
		5,392,151		Nelson	02/21/95
		5,396,066		Ikeda et al.	03/07/95
	╁╌┈┼	5,561,523		Blomberg et al.	10/01/96
·	 	5,629,951		Chang-Hasnain et al.	05/13/97
	1	5,640,133		MacDonald et al.	06/17/97
	-{	5,646,772		Yurke	07/08/97
	+	5,654,819		Goossen et al	08/05/97
	++	5,696,662		Bauhahn	12/09/97

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	Cite No.	Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)		
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OTHER ART - NON PATENT LITERATURE DOCUMENTS

Examiner's	Cite	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation
Initials #	No		(Y/N)
		ANALYSIS OF GRATING LIGHT VALVES WITH PARTIAL SURFACE ELECTRODES, FURLANI et al., J. Appl. Phys. 83 (2), 01/15/98, American Institute of Physics, pp 629-634	

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#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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FORM PTO-1449/A and B (Modified)

Sheet

APPLICATION NO.: 09/975,169

ATTY. DOCKET NO.: P0743/7001

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

FILING DATE:

October 11, 2001

APPLICANT:

Erik R. Deutsch et al.

GROUP ART UNIT:

2872

EXAMINER:

U.S. PATENT DOCUMENTS

Examiner's Initials#	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue	
	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY	
		5,739,945		Tayebati	01/14/98	
		5,905,571		Butler et al.	05/18/99	
		5,933,277		Troxell et al.	08/03/99	
		5,949,568		Koo et al.	09/07/99	
		5,966,235		Walker	10/12/99	
		5,969,848		Lee et al.	10/19/99	
		5,978,127		Berg	11/02/99	
		5,998,906		Jerman et al.	12/07/99	
		6,181,458		Brazas, Jr. et al.	01/30/01	
		6,252,697		Hawkins et al.	06/26/01	

FOREIGN PATENT DOCUMENTS

	Cite	Fore	eign Patent Docu	iment	Name of Patentee or Applicant of Cited	Date of Publication of	Translation	
Examiner's Cite Initials # No.	Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)		
		wo	01/42825	A1	Gutin	06/14/01		
		wo	01/11410	A1	Thackara et al.	02/15/01		

OTHER ART - NON PATENT LITERATURE DOCUMENTS

Examiner's Initials #	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)
		POSITIONING, CONTROL, AND DYNAMICS OF ELECTROSTATIC ACTUATORS FOR USE IN OPTICAL AND RESEARCH SYSTEMS, E.S. HUNG, 08/21/98 thesis Massachusetts Institute of Technology, 107 pages	
		MINIATURE FABRY-PEROT INTERFEROMETERS MICROMACHINED IN SILICON FOR USE IN OPTICAL FIBER WDM SYSTEMS, J.H. JERMAN et al., IEEE 1991 372, International Conf. On Solid-State Sensors and Actuators 1991, pp 372-375	
		MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON, K.E. PETERSEN, IBM Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523	
		LEVERAGED BENDING FOR FULL-GAP POSITIONING WITH ELECTROSTATIC ACTUATION, E.S. HUNG et al., MIT, Solid-State Sensor and Actuator Workshop Hilton Head Island, SC 06/08/98-06/11/98 pp 83-86	

	 	 		 		
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#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

*a copy of this reference is not provided as it was previously cited by or submitted to the office in a prior application, Serial No. ______, filed ______, and relied upon for an earlier filing date under 35 U.S.C. 120 (continuation, continuation-in-part, and divisional applications).

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FORM PTO-	1449/A ar	nd B (Modifi	ied)	.	APPLICATION NO.: 09/975,169	ATTY. DO	OCKET NO.: P0'	743/7001			
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Sheet	3	of	6				· 				
		T			PATENT DOCUMENTS		<u> </u>				
Examiner's Initials #	Cite No.			Kind Code	Name of Patentee or Applicant Document	of Cited	of Cited D	ocument			
	·			FOREIG	N PATENT DOCUMENTS						
Examiner's Initials#	Cite No.	Office/		Kind	Document	t of Cited	Publication of Cited	Translation (Y/N)			
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FORM PTO-1449/A and B (Modified) APPLICATION NO.: 09/975,169 ATTY, DOCKET NO.: P0743/7001 INFORMATION DISCLOSURE FILING DATE: October 11, 2001 STATEMENT BY APPLICANT APPLICANT: Erik R. Deutsch et al. GROUP ART UNIT: 2872 **EXAMINER:** Sheet 6 **U.S. PATENT DOCUMENTS** U.S. Patent Document Date of Publication or of issue Cite Name of Patentee or Applicant of Cited Examiner's of Cited Document No. Initials# Kind Document Number MM-DD-YY Code FOREIGN PATENT DOCUMENTS Date of Foreign Patent Document Name of Patentee or Applicant of Cited Publication of Cite Examiner's Translation Document Cited No. Office/ Initials # Kind (Y/N) Number (not necessary) Document Country Code MM-DD-YY OTHER ART - NON PATENT LITERATURE DOCUMENTS Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the Examiner's Cite Translation Initials# item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue No (Y/N) number(s), publisher, city and/or country where published. DESIGN AND FABRICATION OF 10X10 MICRO-SPATIAL LIGHT MODULATOR ARRAY FOR PHASE AND AMPLITUDE MODULATION, CHUNG et al., Sensors and Actuators 78, Elsevier Science S.A., 1999, pp 63-70 A DESIGN-BASED APPROACH TO PLANARIZATION IN MULTILAYER SURFACE MICROMACHINING, MALI et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, Micromech. Microeng. 9 (1999) pp 294-299 VARIABLE GRATINGS FOR OPTICAL SWITCHING: RIGOROUS ELECTROMAGNETIC SIMULATION AND DESIGN, GANI et al., Opt. Eng. 38(3) 552-557, (March 1999) Soc. of Photo-Optical Ins. Eng. pp 552-557 DIFFERENTIAL CAPACITIVE POSITION SENSOR FOR PLANAR MEMS STRUCTGURES WITH VERTICAL MOTION,, HORENSTEIN, et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, Elsevier Science S.A. 07/12/99 pp 53-61 CONTINUOUS-MEMBRANE SURFACE-MICROMACHINED SILICON DEFORMABLE MIRROR, BIFANO et al., Soc.

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